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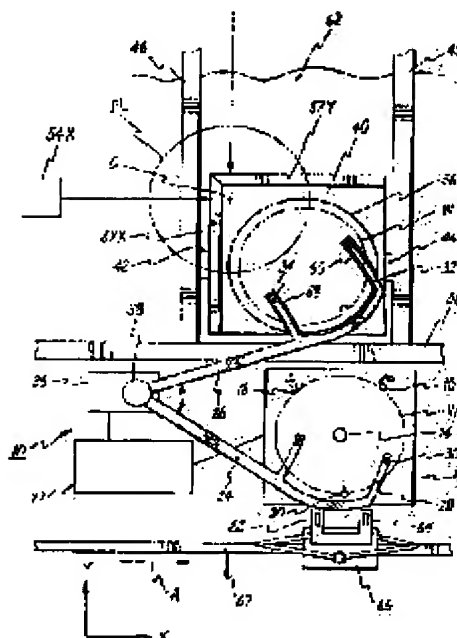
## (54) SUBSTRATE CARRIER SYSTEM

## (57)Abstract:

**PROBLEM TO BE SOLVED:** To cut down the replacement times of substrates by a method wherein carrier arms are driven in parallel with a stage shifting surface while a substrate holding part formed of recession trenches capable of inserting the carrier arm on the contact surface with the substrate on the stage either one out of the carrier arm or the substrate holding part is driven on the stage shifting surface in the orthogonal direction.

**SOLUTION:** Carrier arms 24, 26 where base ends are respectively connected to the arm driving mechanism 38 comprising an arm driving device 36 in a cantilever state so that the carrier arms 24, 26 may be independently driven in the horizontal surface and in the upper and lower directions by this arm driving mechanism 38.

Besides, a wafer holder 56 is mounted on an XY stage 40 as a substrate holder holding wafers W. On this wafer holder 56, a pair of circular recession trenches 58, 60 capable of inserting a pair of pawl parts 32 of a rotary wafer unloading rotary carrier arm 26 are formed. Furthermore, rotary carrier arms 24, 26 are composed to be vertically movable.



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